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10/723,794 11/26/2003 Yu-Chang Jong 252011-1790 9066 47390 7590 01/25/2005 EXAMINER THOMAS, KAYDEN, HOSTEMEYER & RISLEY LLP DANG, TRUNG Q 100 GALLERIA PARKWAY SUITE 1750 ART UNIT PAPER NUMBER	APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
THOMAS, KAYDEN, HOSTEMEYER & RISLEY LLP 100 GALLERIA PARKWAY DANG, TRUNG Q	10/723,794	11/26/2003	Yu-Chang Jong	252011-1790	9066	
100 GALLERIA PARKWAY	47390	47390 7590 01/25/2005			EXAMINER	
		-	DANG, TRUNG Q			
				ART UNIT	PAPER NUMBER	
ATLANTA, GA 30339 2823		GA 30339		2823		

DATE MAILED: 01/25/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)			
	10/723,794	JONG ET AL.			
Office Action Summary	Examiner	Art Unit			
	Trung Dang	2823			
The MAILING DATE of this communication app	1 -	orrespondence address			
Period for Reply		•,			
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be timy within the statutory minimum of thirty (30) days will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	nely filed s will be considered timely. the mailing date of this communication. O (35 U.S.C. § 133).			
Status					
1)⊠ Responsive to communication(s) filed on 06 De	ecember 2004.				
· <u>-</u>					
	, 				
Disposition of Claims					
4) ☐ Claim(s) 1-31 is/are pending in the application. 4a) Of the above claim(s) is/are withdraw 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 1-31 is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or	vn from consideration.				
Application Papers					
9)☐ The specification is objected to by the Examine 10)☒ The drawing(s) filed on 26 November 2003 is/a Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11)☐ The oath or declaration is objected to by the Ex	re: a) \square accepted or b) \square objected drawing(s) be held in abeyance. See ion is required if the drawing(s) is obj	e 37 CFR 1.85(a). ected to. See 37 CFR 1.121(d).			
Priority under 35 U.S.C. § 119					
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the prior application from the International Bureau * See the attached detailed Office action for a list	s have been received. s have been received in Application rity documents have been receive u (PCT Rule 17.2(a)).	on No ed in this National Stage			
2.2 2	2 2234 35pi33 not 1300110				
Attachment(s)	_				
 Notice of References Cited (PTO-892) Notice of Draftsperson's Patent Drawing Review (PTO-948) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date 	4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:				

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DETAILED ACTION

Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-31 are rejected under 35 U.S.C. 103(a) as being unpatentable over Furuhara et al. of record in view of Abeln et al. (US 6,207,510).

With reference to Figs. 6-13 and the description thereof, the reference teaches substantially the claimed invention in that it discloses a method of forming an integrated circuit having gate oxide layers with multiple thicknesses, comprising the steps of:

providing a substrate having a first active region 3000, a second active region 2000, and a third active region 1000;

performing a first oxidation to form a first oxide layer **50aL** on the substrate (Fig. 6);

depositing a blanket high temperature oxide layer (HTO) **50bL** with a first thickness (100–200 Å) overlying the substrate (Fig. 7);

forming a first photoresist layer R3 on the high temperature oxide layer except over the second active region 2000;

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etching the high temperature oxide layer and the underlying first oxide layer on the second active region using the first photoresist layer as an etch mask to expose the substrate (Fig. 8);

removing the first photoresist layer;

performing a second oxidation to form a second oxide layer 22aL with a second thickness (30-150 Å) less than the first thickness on the second active region 2000 (Fig. 9);

forming a second photoresist layer R5 overlying the substrate except over the third active region 1000;

removing the high temperature oxide layer and the underlying first oxide layer on the third active region to expose the substrate (Fig. 11);

removing the second photoresist layer;

performing a third oxidation to form a third oxide layer 20L with a third thickness (10 - 100 Å) less than the first thickness on the third active region and on the second oxide layer on the second active region (Fig. 12); and

forming a first gate 34 on the high temperature oxide layer on the first active region, a second gate 32 on the second oxide layer on the second active region, and a third gate 30 on the third thermal oxide layer on the third active region (Fig. 13).

Furuhata differs from the amended independent claims 1, 14 and 26 in that while Furuhata shows in Fig. 7 a non-planar high temperature oxide (HTO) layer

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50bL as a result of depositing the HTO layer 50bL on a substrate having the field insulation 18 formed by local oxidation of silicon (LOCOS), the claims call for a corresponding HTO layer having a substantially planar top surface.

However, in the same field of endeavor, Abeln teaches that device isolation regions can be formed by shallow trench isolation (STI) method to produce a substantially planar surface or by alternative methods including LOCOS (Fig. 2 and col. 4, lines 22-40).

It would have been obvious to one of ordinary skill in the art to modify the primary reference by forming the field insulation 18 by STI method so as to produce substantially planar surface as suggested by Albeln because both STI and LOCOS are recognized in the art as alternatives in the making of device isolation, and the substitution of one technique for another art-recognized technique to make the same would have been within the level of one skilled in the art, absent a showing of criticality or unexpected result by applicants. Note that the HTO layer 50bL when deposited on a substrate in which active regions are isolated by STI would result in having a substantially planar top surface as claimed.

For claim 3, see col. 8, lines 24-28 for the transistor 100 (corresponding to the claimed third device region) that is operated at a first voltage level (1.8-3.3V (col.4, lines 5-6) is a core device region such as sense amplifier.

For claims 7 and 8, see col.8, lines 29-37 and col. 4, lines 6-12 for transistors **200** and **300**, which correspond to the claimed second and first devices, respectively.

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As for the value of the first thickness recited in claims 11 and 28, although Furuhata teaches the HTO layer 50bL having a first thickness in a range of 100-200 Å as noted above, the difference in thickness will not support the patentability of the subject matter encompassed by the prior art unless there is evidence indicating such thickness is critical. "[W]here the general conditions of a claim are disclosed in the prior art, it is not inventive to discover the optimum or workable range by routine experimentation." See In re Aller, 220 F.2d 454, 456, 105 USPQ 233, 235 (CCPA 1955); In re Hoeschele, 406 F.2d 1403, 160 USPQ 809 (CCPA 1969); Merch & Co. Inc. v. Biocraft Laboratories Inc., 874 F.2d 804, 10 USPQ2d (Fed.cir), cert. denied, 493 U.S. 975 (1989); In re Kulling, 897 F.2d 1147, 14 USPQ2d 1056 (Fed. Cir. 1990); and *In re Geisler*, 116 F.3d 1465, 43 USPQ2d 1362 (Fed. Cir. 1997). Furthermore, the specification contains no disclosure of either the critical nature of the claimed thickness range or any unexpected results arising therefrom. Where patentability is said to be based upon particular chosen dimensions or upon another variable recited in the claim, the applicant must show that the chosen dimensions are critical. In re Woodruff, 919 F.2d, 1575, 1578, 16 USPQ2d, 1936 (Fed. Cir. 1990).

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Response to Arguments

2. Applicant's arguments with respect to claims 1, 14, and 26 have been considered but are most in view of the new ground(s) of rejection.

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Conclusion

3. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, THIS ACTION IS MADE FINAL. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Trung Dang whose telephone number is 571-272-1857. The examiner can normally be reached on Mon-Friday 9:30am-6:00pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on 571-272-1855. The fax

phone number for the organization where this application or proceeding is assigned

is 703-872-9306.

Information regarding the status of an application may be obtained from the

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Should you have questions on access to the Private PAIR system, contact the

Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Trung Dang Primary Examiner

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